



**The Abdus Salam
International Centre for Theoretical Physics**



1936-26

**Advanced School on Synchrotron and Free Electron Laser Sources
and their Multidisciplinary Applications**

7 - 25 April 2008

**Scanning Photoemission Microscopy:
Instrumentation and Methodology**

Luca Gregoratti
Sincrotrone Trieste SCpA

Scanning Photoemission Microscopy: Instrumentation and Methodology

Luca Gregoratti

Sincrotrone Trieste SCpA, Area Science Park, SS14-Km163.5, 34012 Trieste, Italy

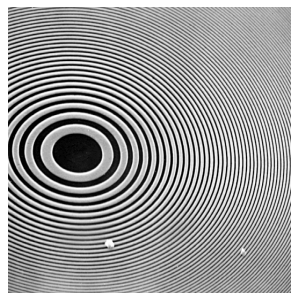
email: luca.gregoratti@elettra.trieste.it

Scanning

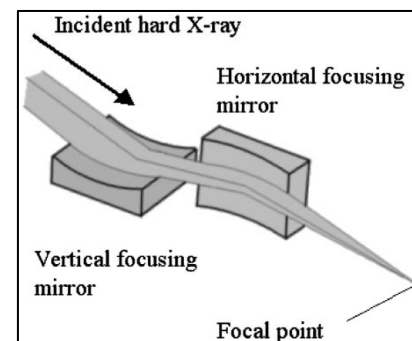
SPEM

Zone Plates lenses

- Elettra
- ALS
- SRRRC
- PAL



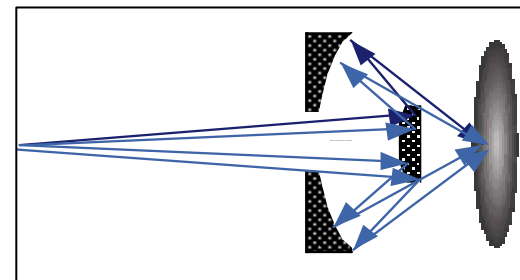
Kirkpatrick-Baez



Focusing mirrors

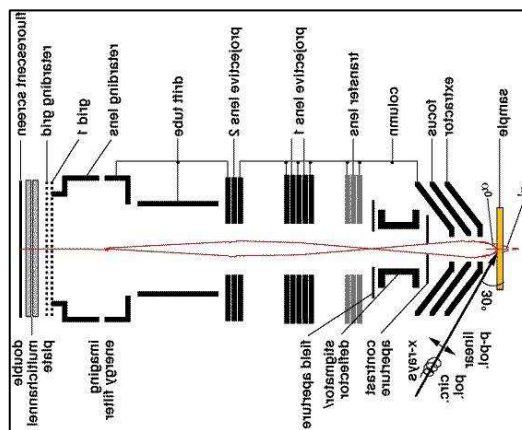
Schwarzschild mirrors

- Elettra
- Madison

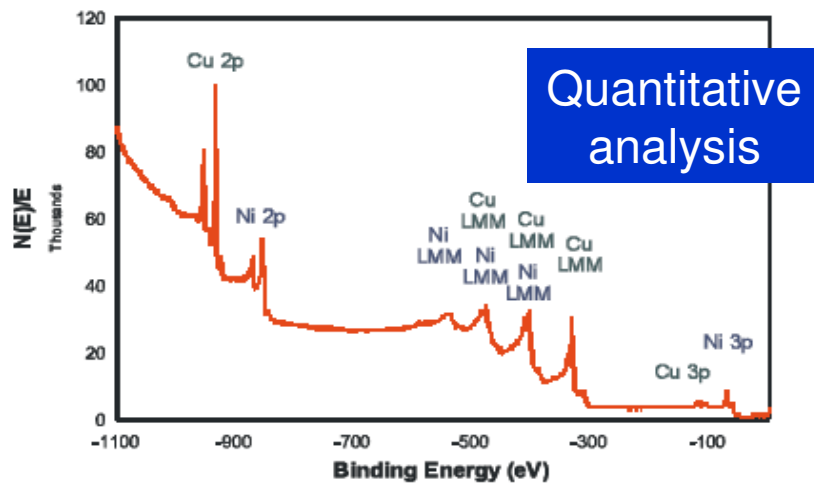


No scanning

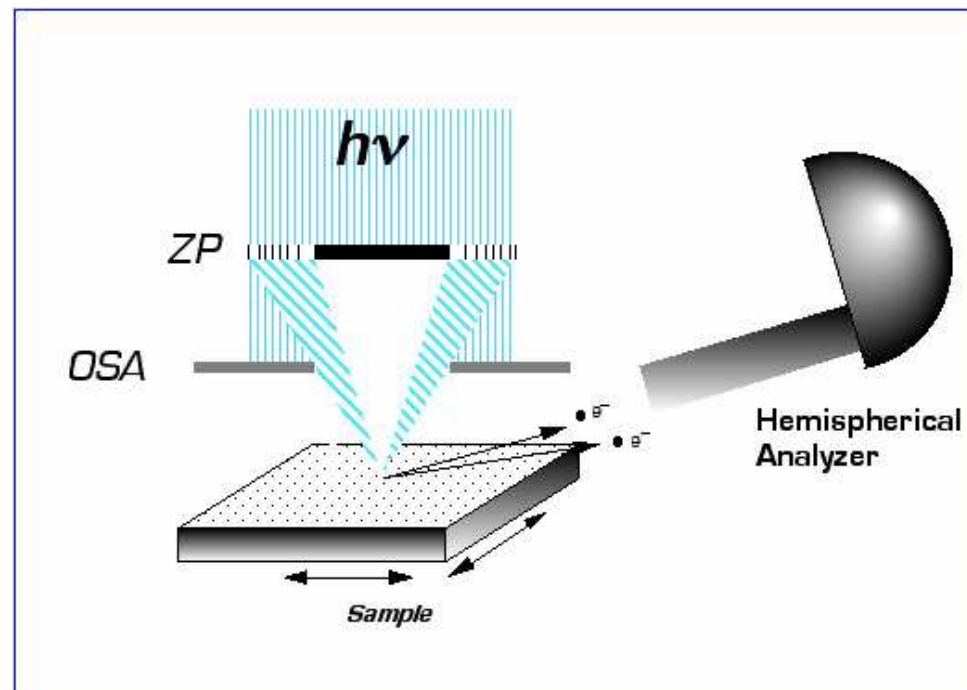
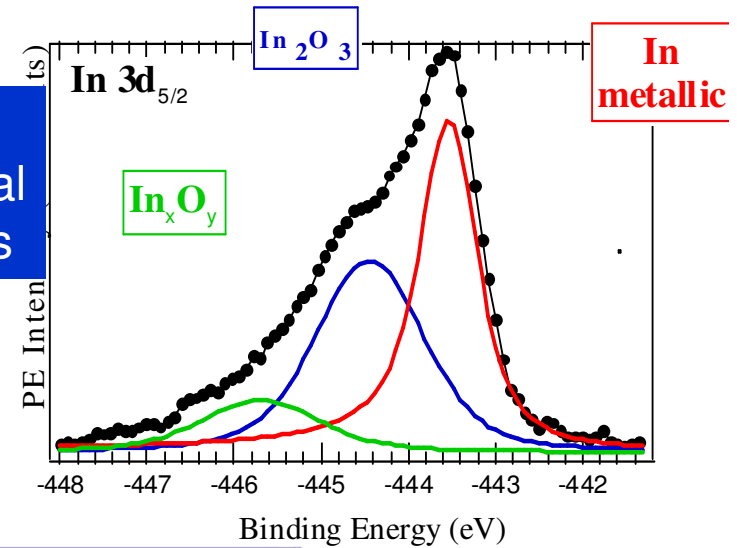
**XPEEM
(XPEEM, SPELEEM)**



- Elettra
- SLS
- MAX-lab
- BESSY
- Madison
- Spring8



Fine
Chemical
analysis



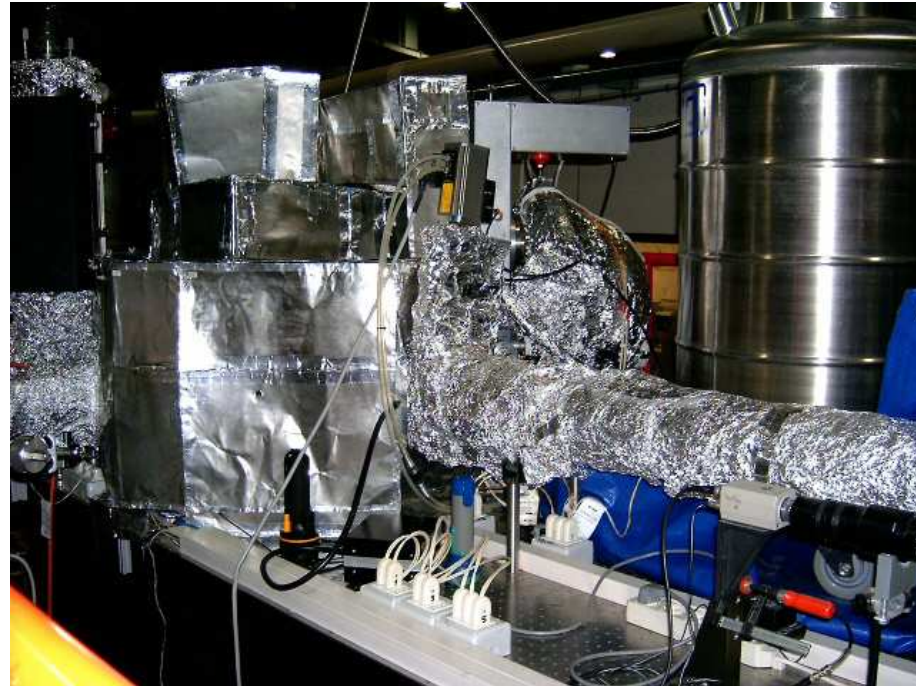
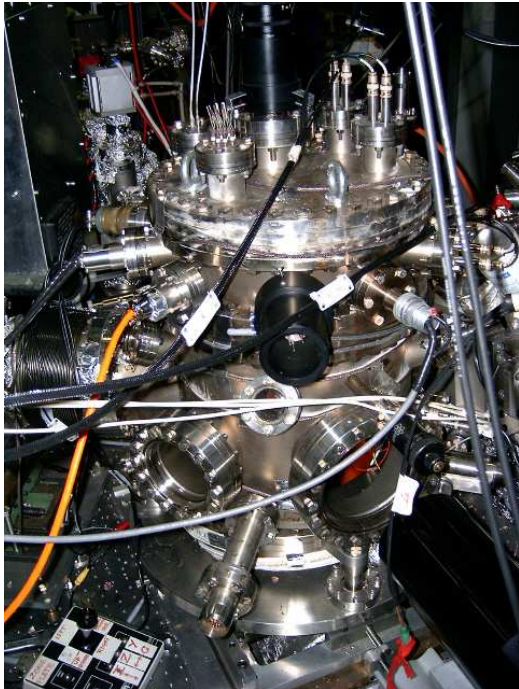
Outline:

**Ingredients of a Scanning Photoemission Microscope
(SPEM) based on Zone Plates**

- Vacuum chambers
- Sample and optics manipulators
- Sample holders
- Electron analyzers
- Electron detectors

Vacuum chambers

- No standard geometry
- Dimensions depends mainly from the size of the manipulators
- Large flanges for the manipulators ($>CF200$)
- Geometry limits the possibility of in-situ experiments



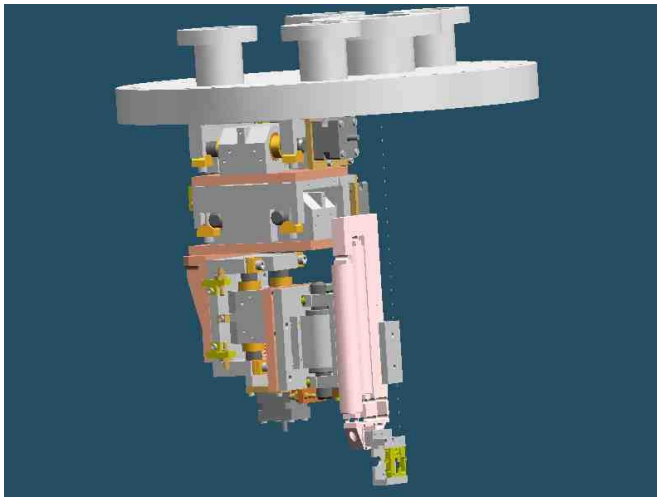
Manipulators

Sample

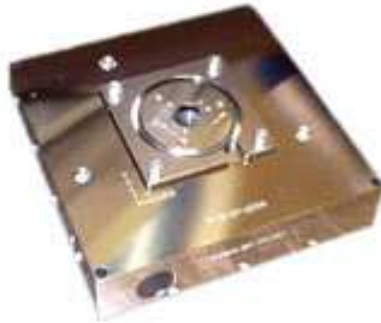
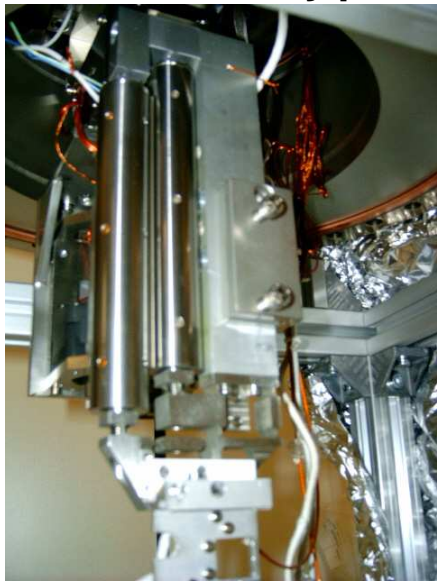
- Large scanning range ($>1\text{mm}$) with large steps ($1\text{-}100\text{ }\mu\text{m}$)
- Small scanning range ($<3\text{mm}$) with small steps ($10\text{-}50\text{ nm}$)
- The most common choice is to use two kind of motors: stepper (for large scans) and piezo (for small scans)
- Compact design to improve the stability

Optics (ZP+OSA)

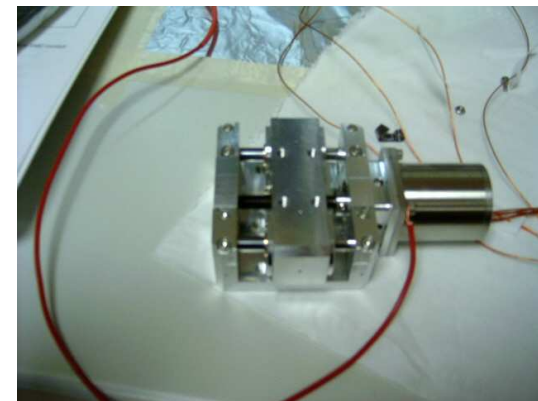
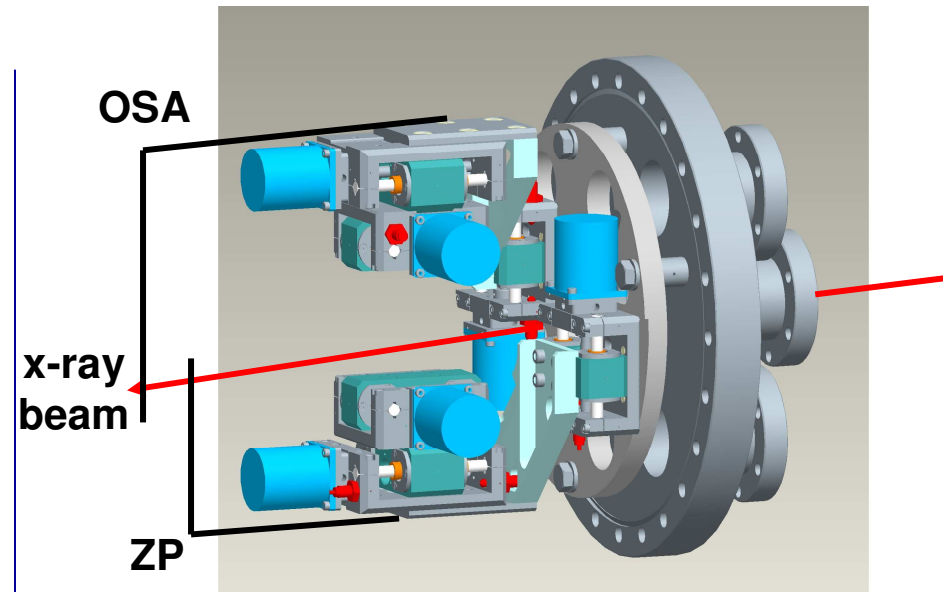
- 6-axis needed: 3 for the ZP and 3 for the OSA
- Typical range: $10 - 15\text{ mm}$
- Movement resolution of $1\text{-}3\text{ }\mu\text{m}$
- Only one type of motors needed (stepper or inchworm)
- Compact design to improve the stability



x-y piezo stages

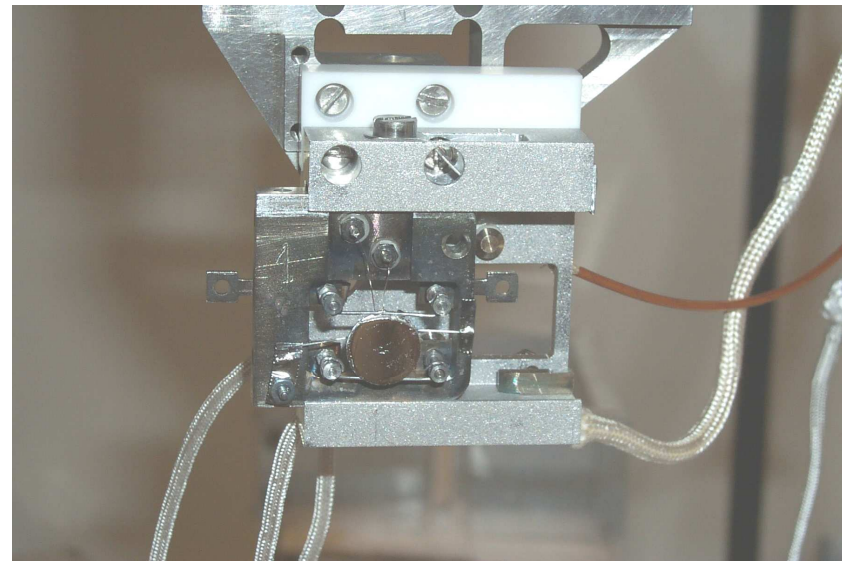
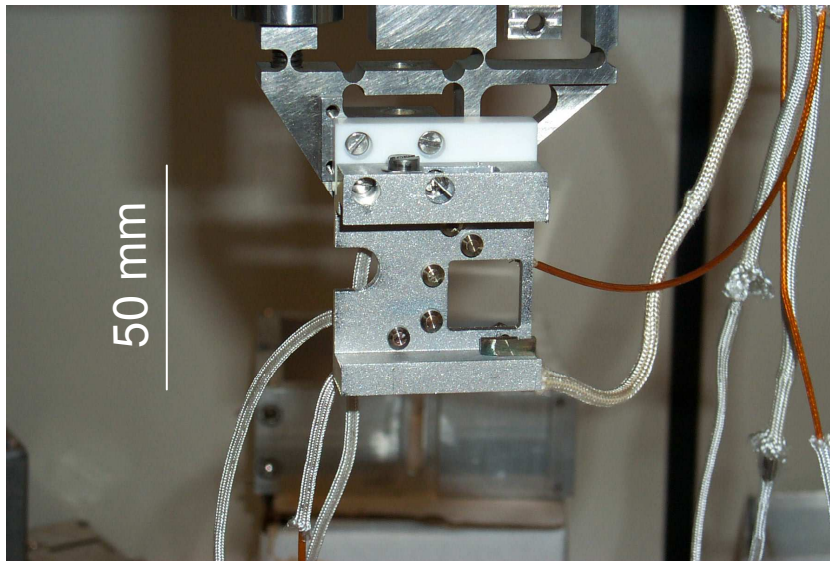


1 axis coarse translation stage



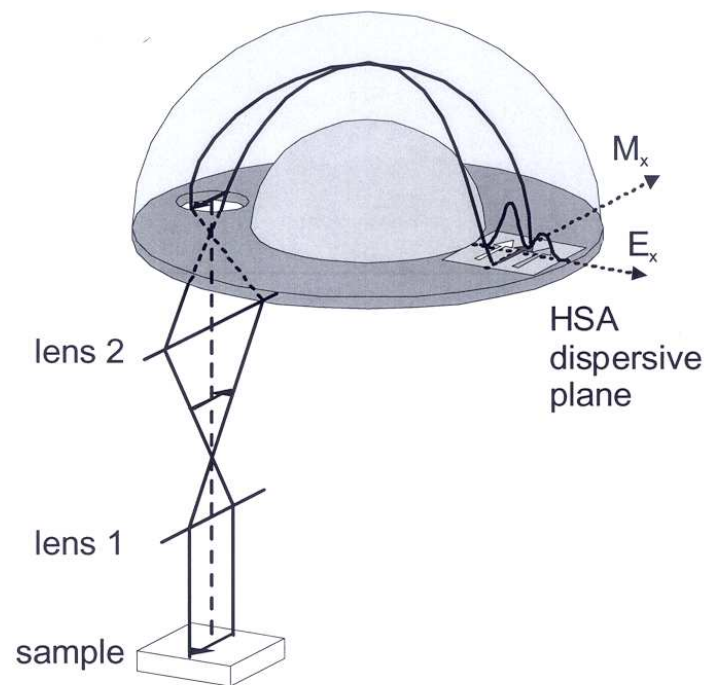
Sample holders

- Cabling used for the contacts (heating, grounding, potentials, etc.) must not interfere with the scanning motion.
- Cooling needs special design
- In most of the cases sample holders are home designed (or modified from standard designs)

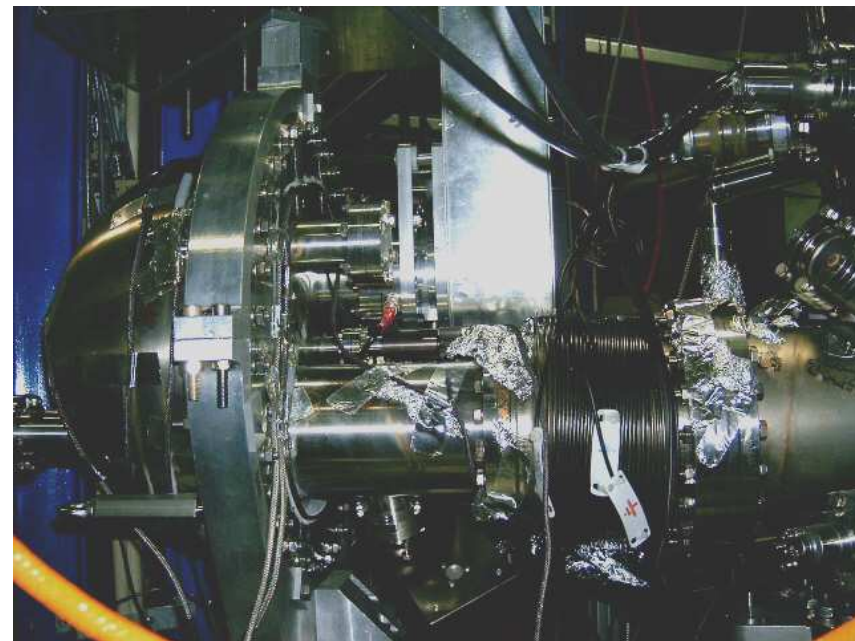


Electron analyzers

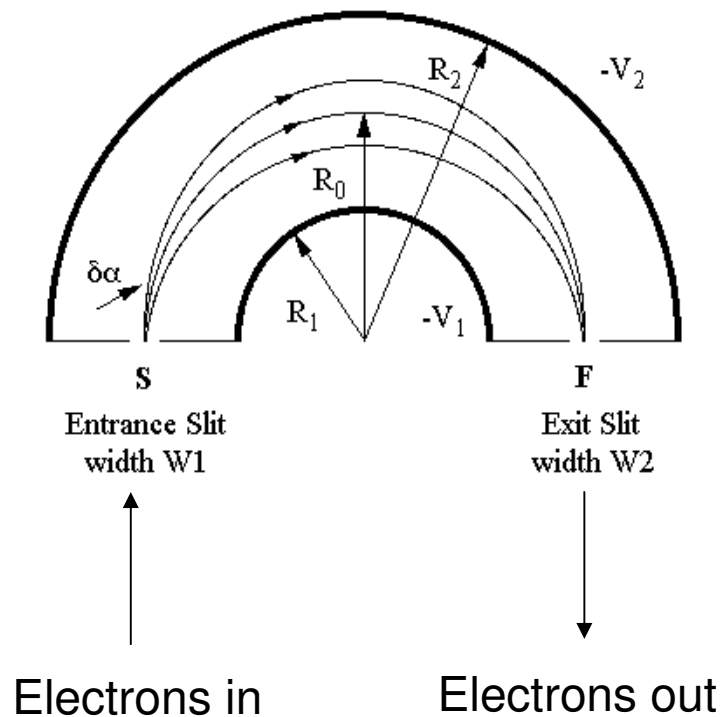
- The most used type of electron analyzer is the Hemispherical Electron Analyzer (HEA)
- Due to geometrical constraints the detection is mainly grazing



Electron analyzer of the SPEM



Potential along the median surface: $V_0 = \frac{V_1 R_1 + V_2 R_2}{2R_0}$



Tangential injection

$$V_1 = V_0 \frac{R_2}{R_1} \quad V_2 = V_0 \frac{R_1}{R_2}$$

$$E_0 = eV_0$$

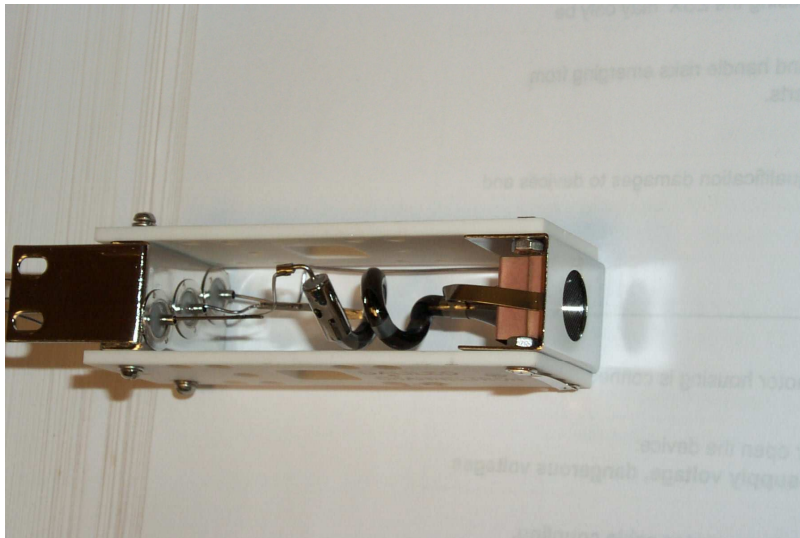
Angled injection

$$\Delta R = 2 R_0 \left[\frac{\Delta E}{E} - (\delta\alpha)^2 \right]$$

Electron detectors

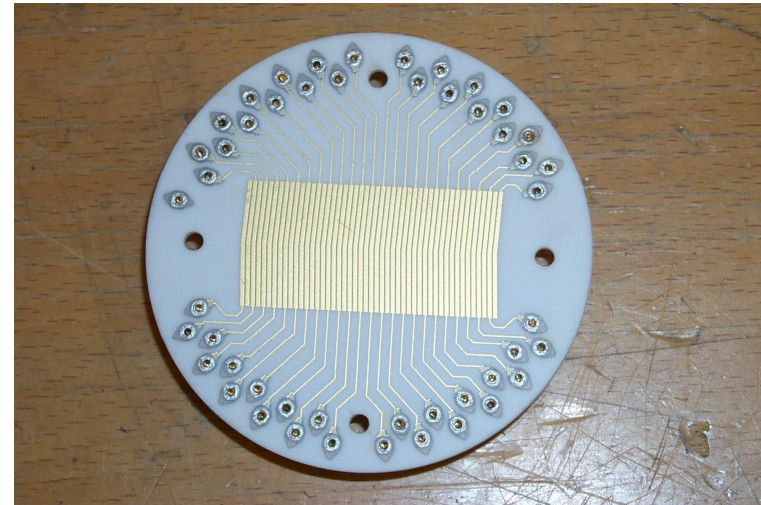
Single channel

- Single channeltron
- Single Au plated anode
- Not very diffused

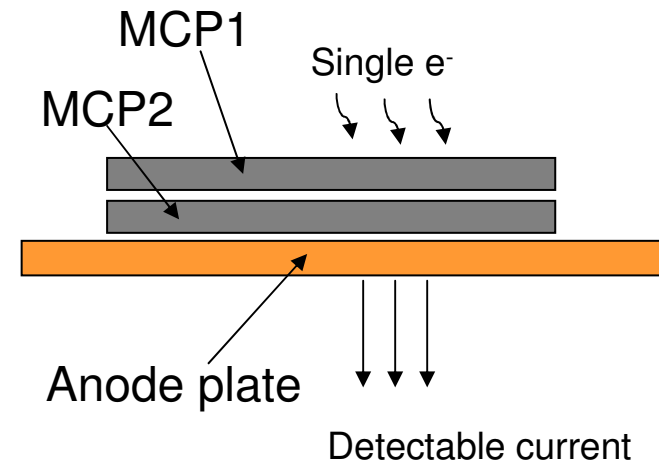
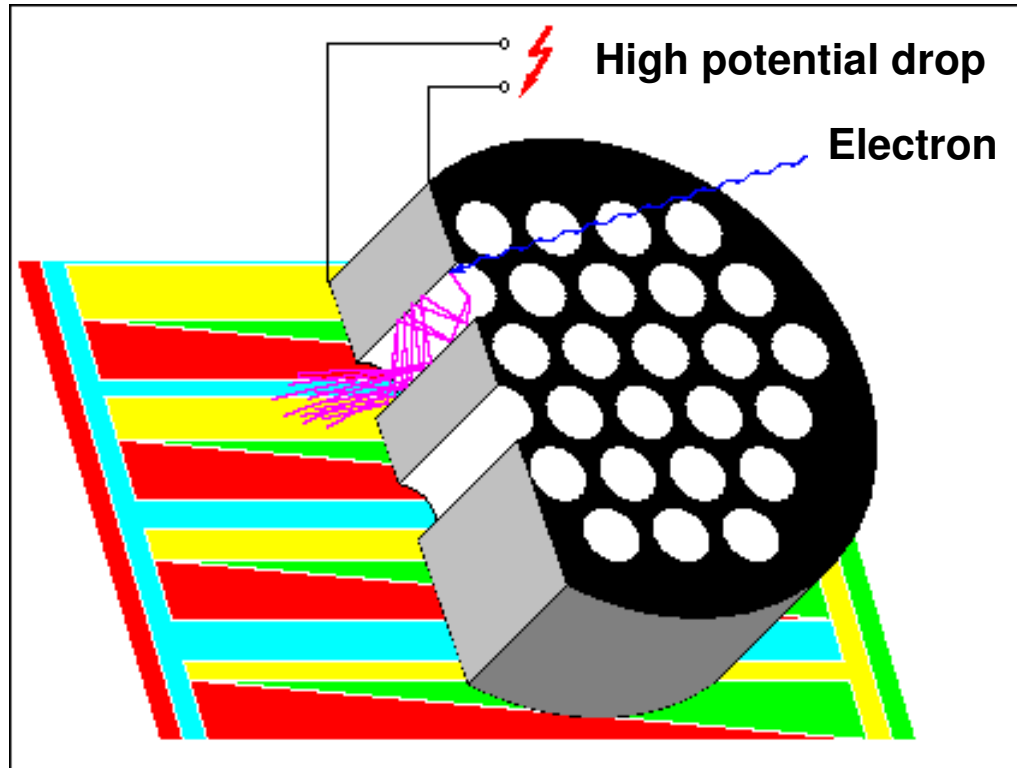


Multi channel

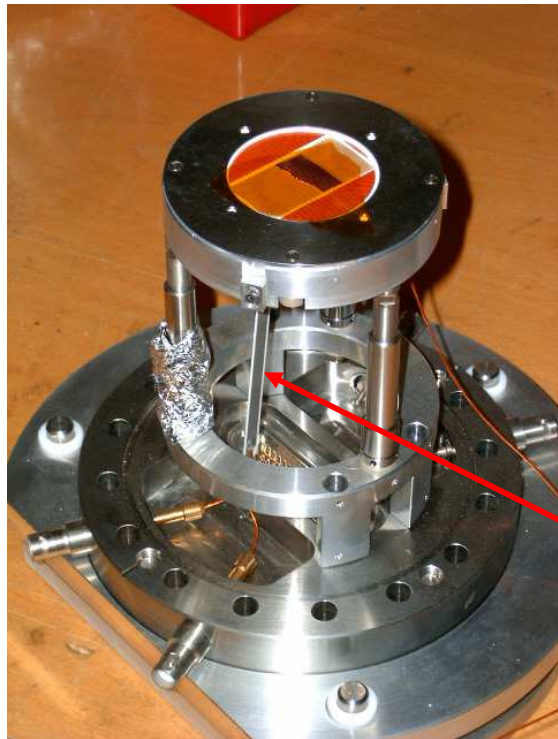
- Array of channeltron (low number of channels)
- Multi Au plated anodes (100 channels)
- 2D-CCD detectors



Electron detectors based on micro channel plates



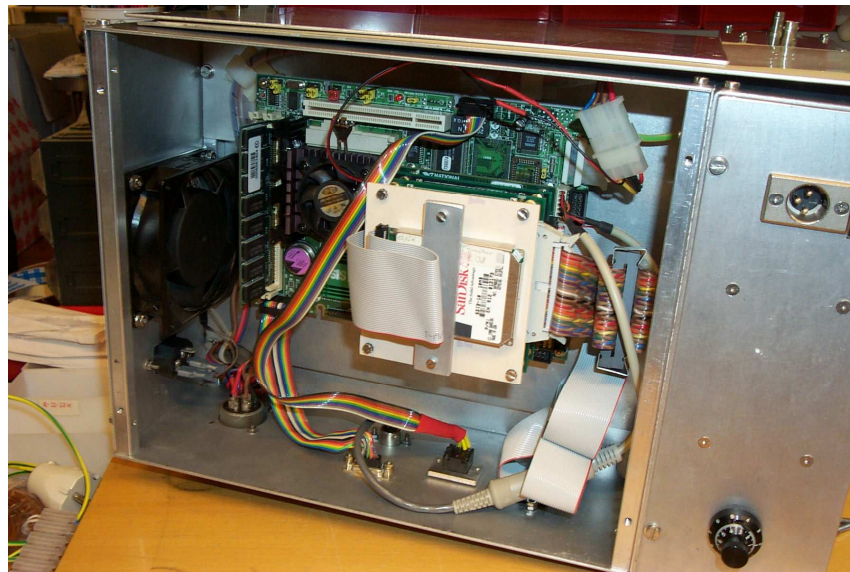
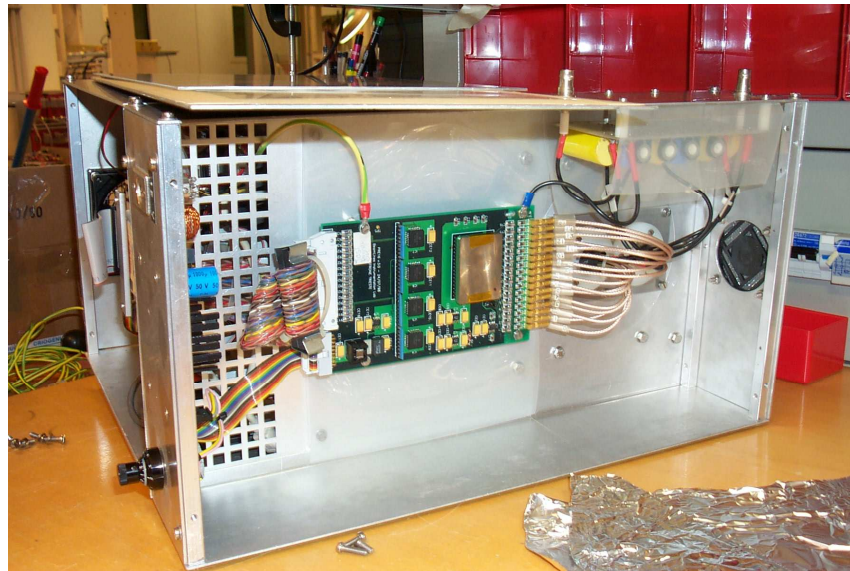
The Microchannel Plate (MCP) consists of millions of very-thin, conductive glass capillaries (4 to 25 micro meters in diameter) fused together and sliced into a thin plate. Each capillary or channel works as an independent secondary-electron multiplier to form a two-dimensional secondary-electron multiplier.



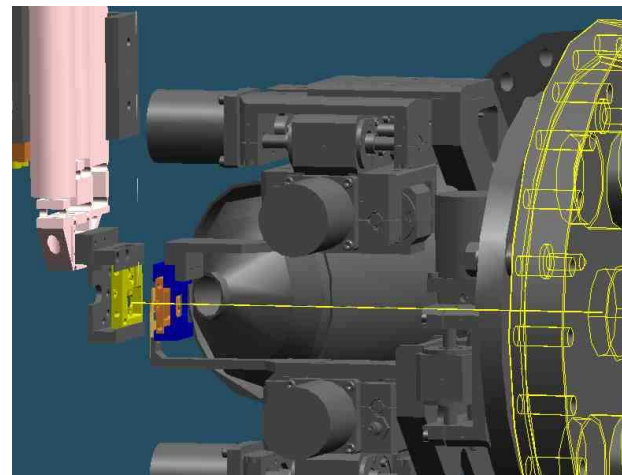
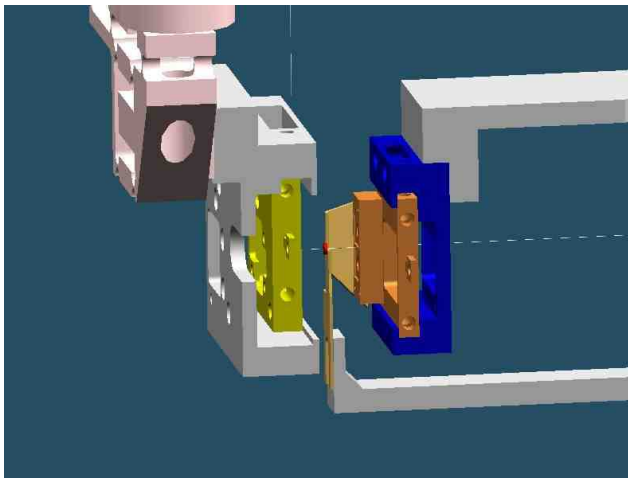
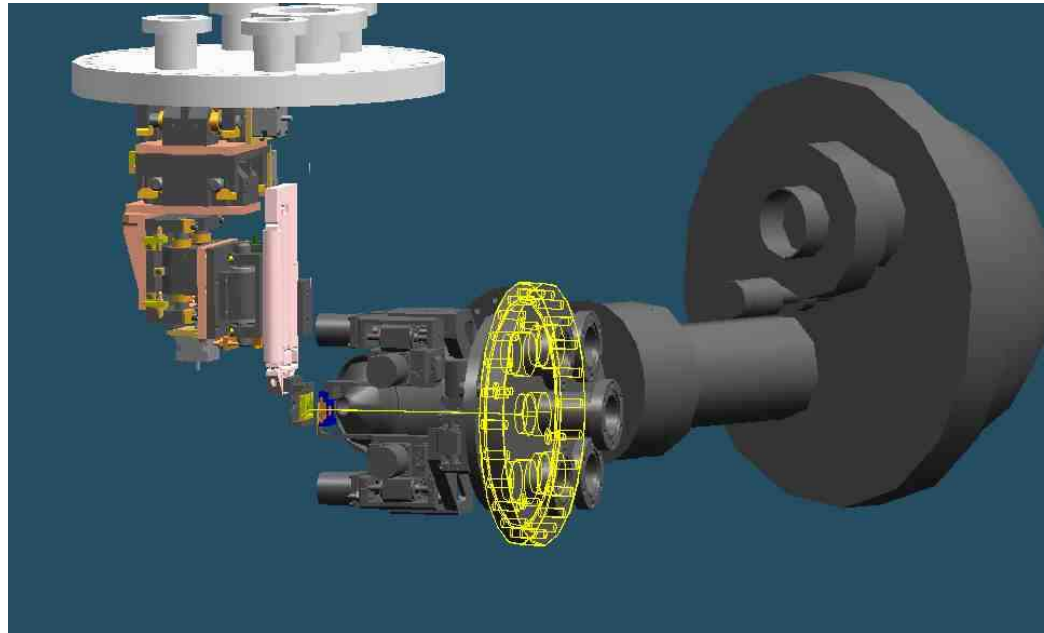
Vacuum
compatible
condensor

Electron Detector Electronics

- Discriminators
- Preamplifiers
- Counters

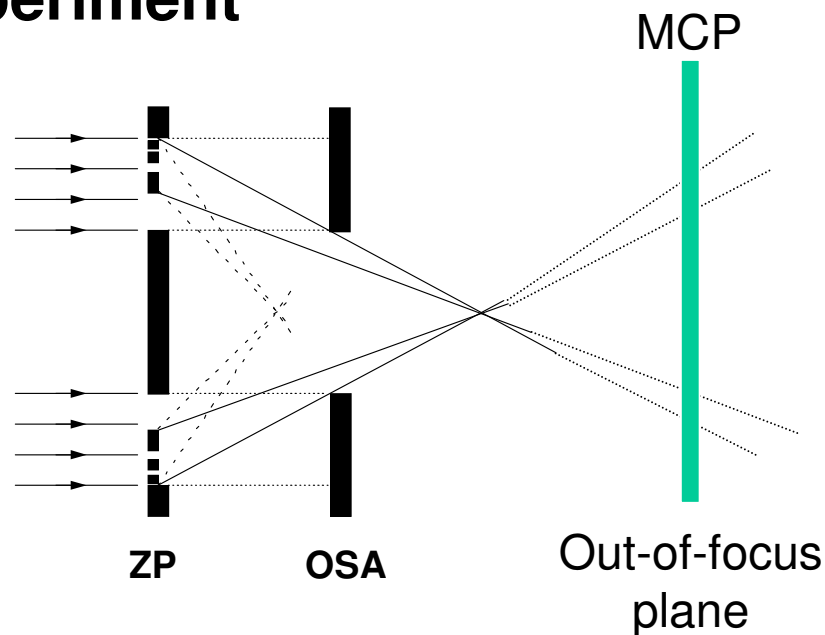
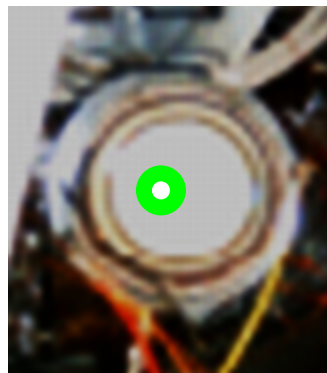
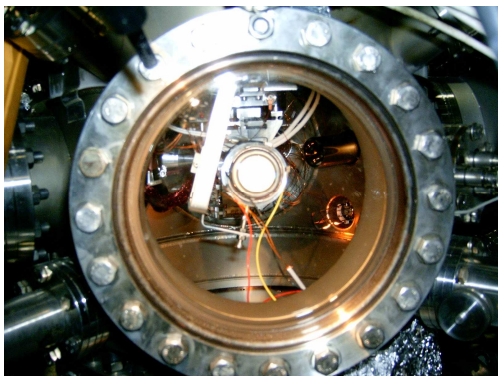


Final layout of the experimental chamber



Start-up of an experiment

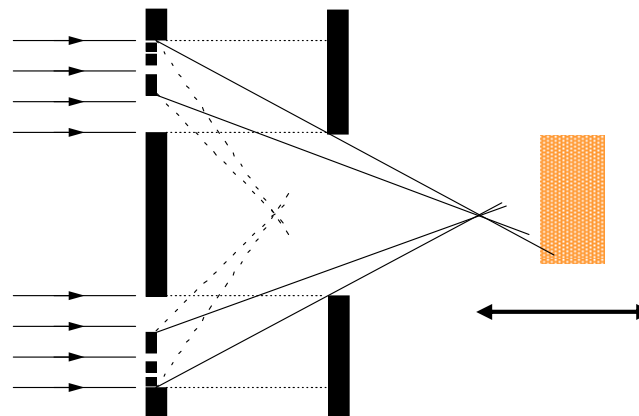
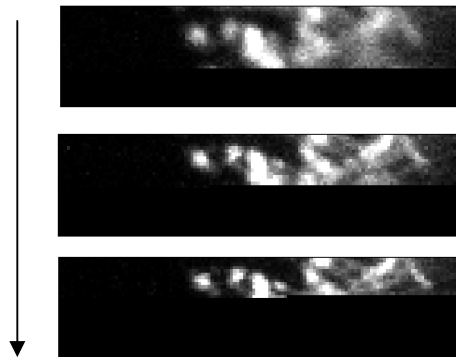
1. Optics alignment



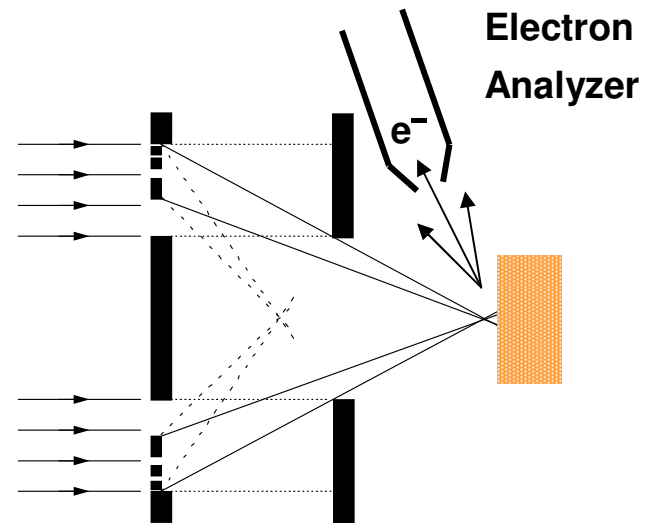
2. Sample on the x-ray focus

$$DOF = \frac{\delta r}{D} f_m$$

Typical: 5-15 μ m



3. Analyzer adjustment



4. Data acquisition

- Images: electron analyzer set to a fixed energy and sample rastered
- Photoemission Spectra: sample fixed and energies scanned

Image analysis

- Nature of the contrast in the images
- Getting the chemical information out of the artefacts
- Multichannel detection

- Chemical inhomogeneity

Ni islands on Si

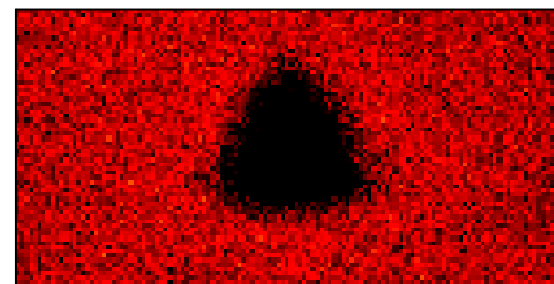
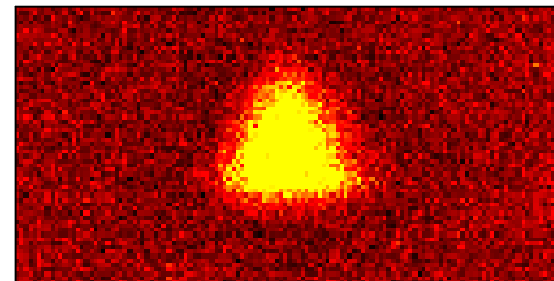
Image on Ni

Ni island

Si substrate

Image on Si

6 μm



Au patch on Rh(110)

Image on Rh

16 μm



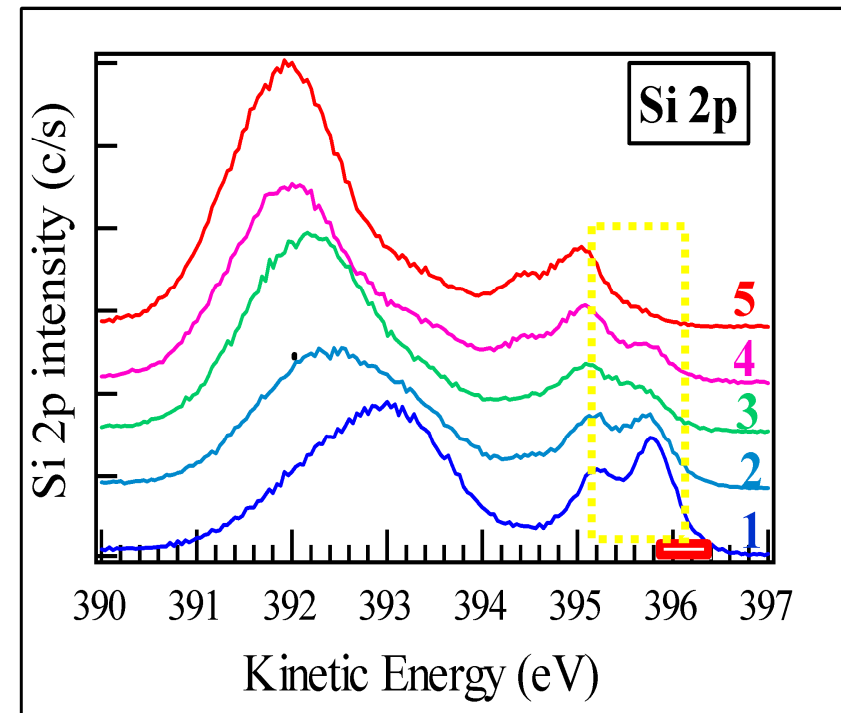
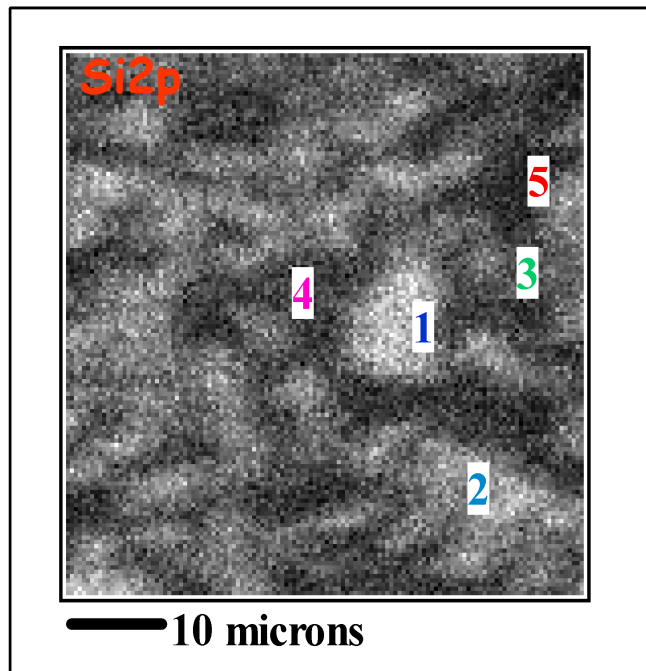
Image on Au



- Topography

- Other sources of contrast

charging



Getting the chemical information out of the artefacts

Artefacts

1. Topography
2. Beam induced effects:
 - C deposition (residual gases)
 - O₂ reduction
 - Charging
3. Background level

How to remove the topographic contribution

$$I = \frac{I_{peak} - I_{bkg}}{I_{peak} + I_{bkg}}$$

$$I = \frac{I_{peak} - I_{bkg}}{I_{bkg}}$$

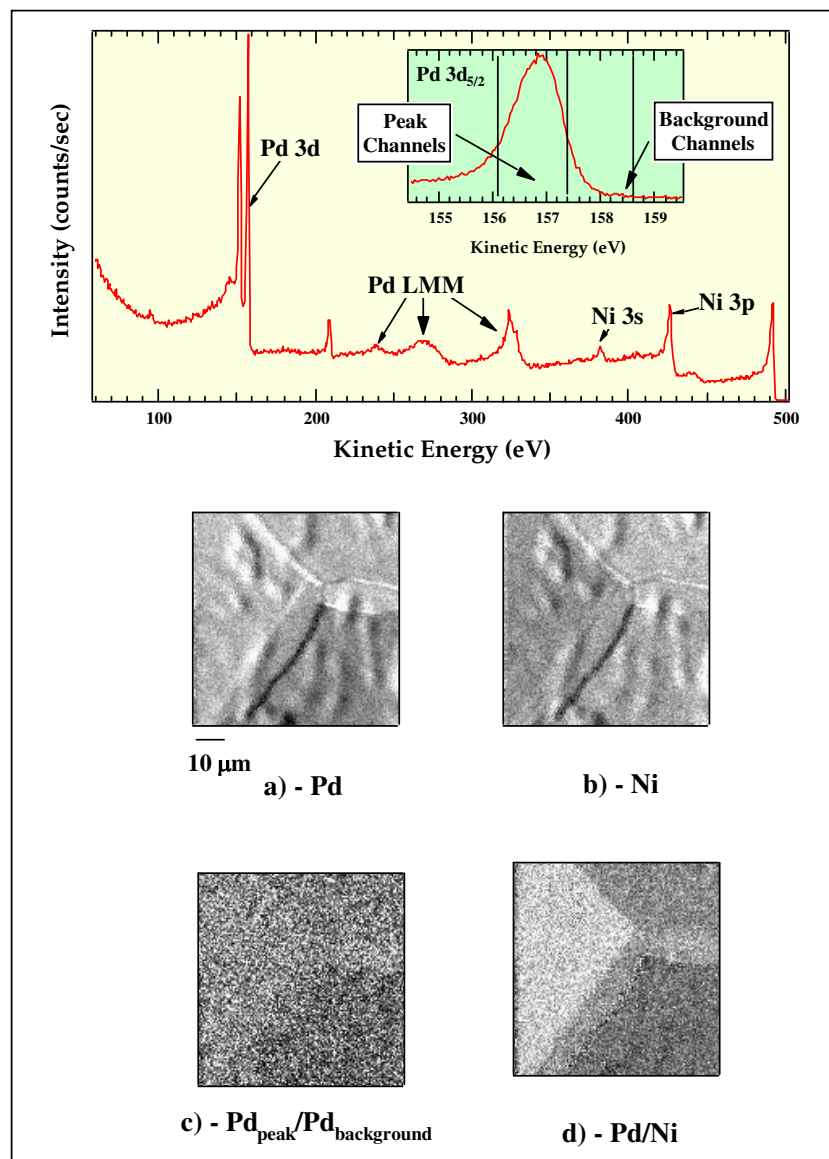
$$I = \frac{I_{peak}}{I_{bkg}}$$

Which I_{bkg} ?

- $I_{bkg \text{ left}}$
- $I_{bkg \text{ right}}$
- $I_{bkg (left+right)}$
- *secondaries*

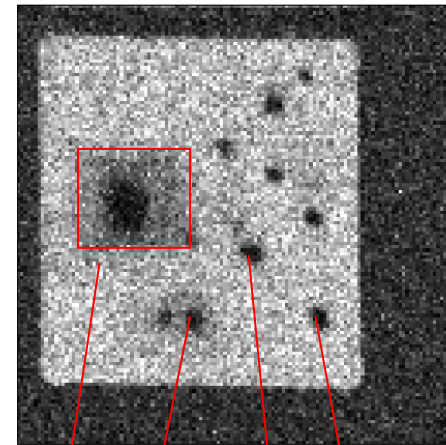
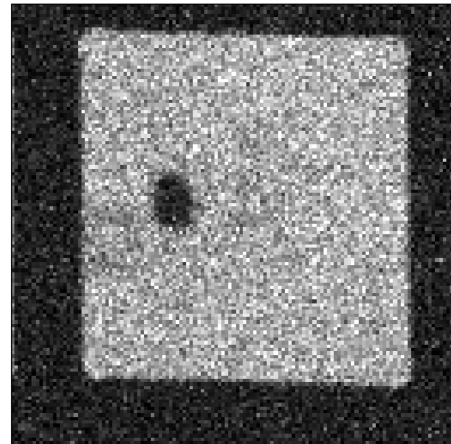
sometimes
only:

$$\frac{I_{peak1}}{I_{peak2}}$$



C growth

SiO_x sample
Si2p maps

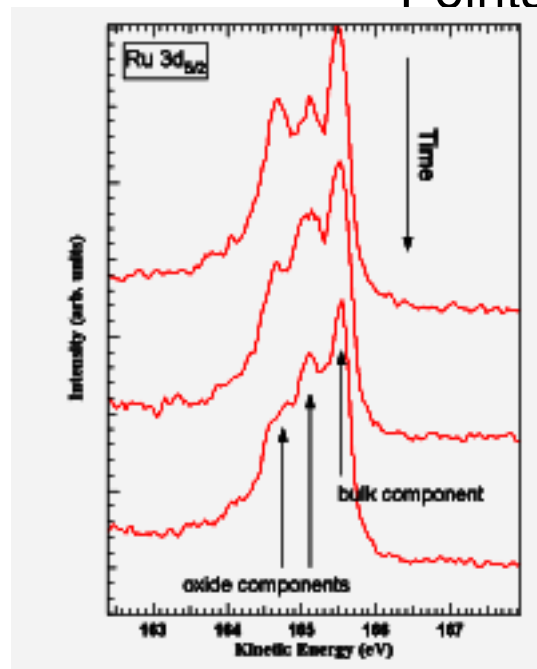


60 μm

Points irradiated (>10 min)

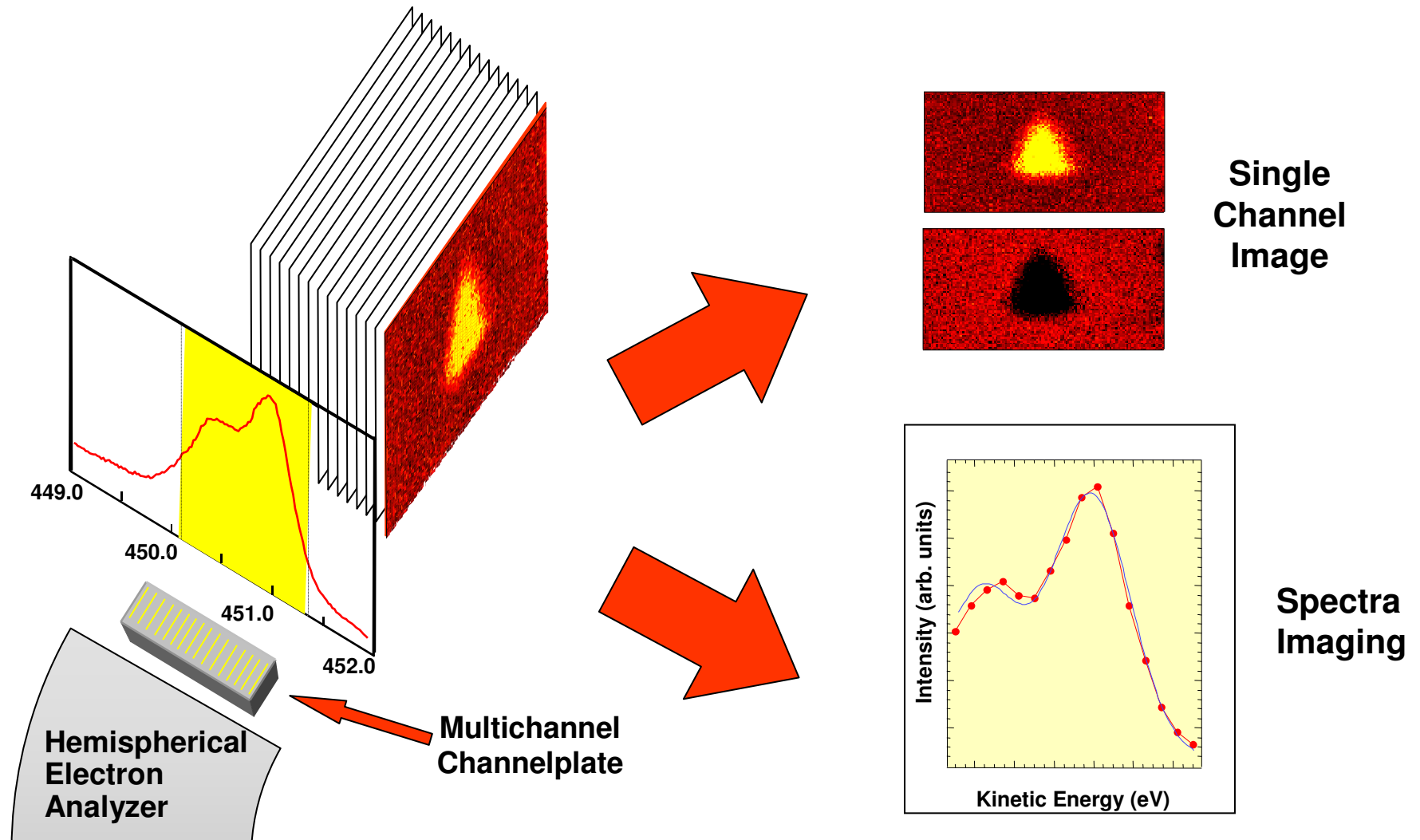
O₂ reduction

RuO_x sample



Each spectrum every 1 min

Multichannel detection



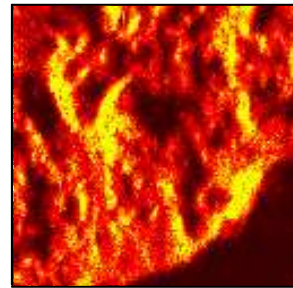
Single Channel Analysis

Carbon nanotubes on SiC

R. Larciprete – Enea - Italy

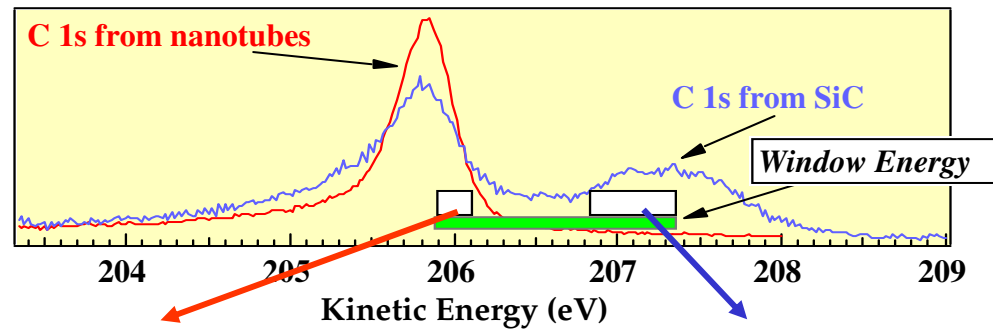
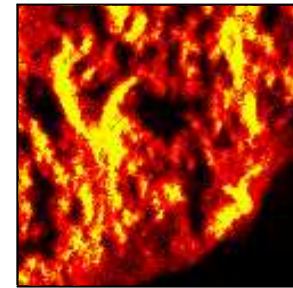
C 1s map:
integration
over the
window energy

a)

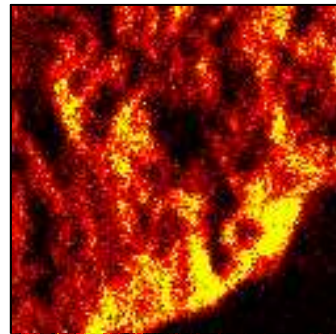


64
 μm

b) Topography
map
(C 1s
background
at 215 eV)

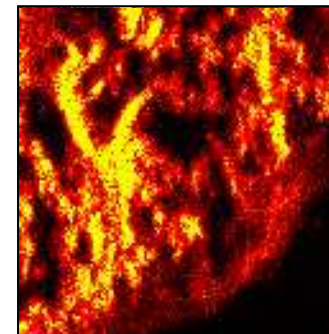


c)

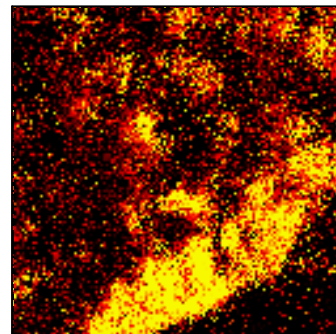


Selected
energy
maps

d)

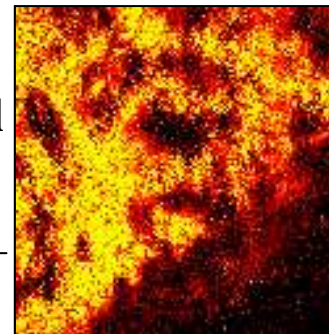


e)



C1 1s
Chemical
maps

f)



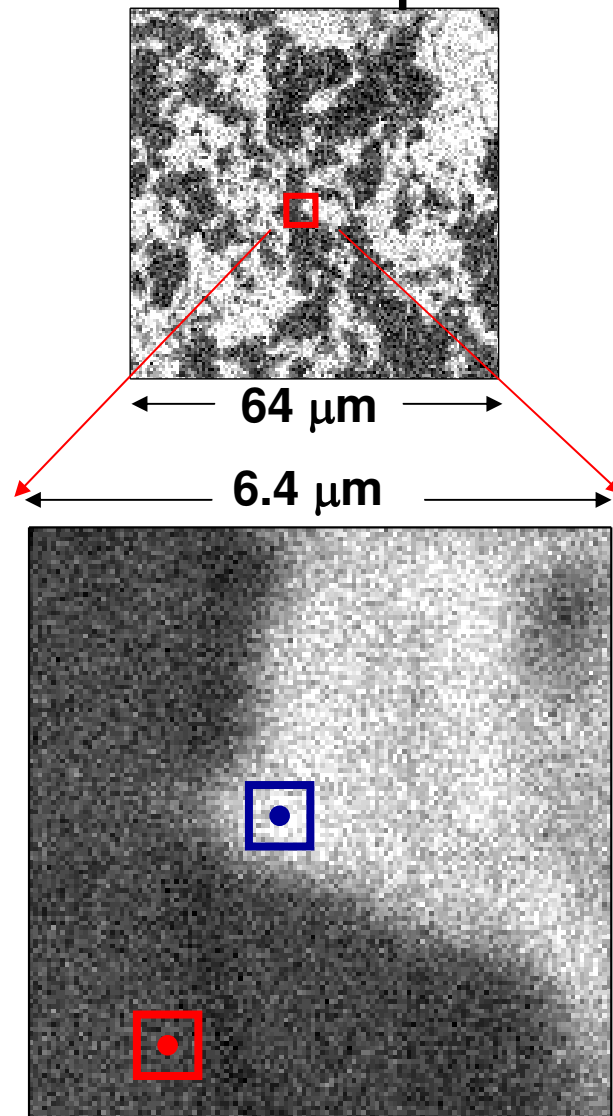
c)
b)

d)
b)

Spectra Imaging

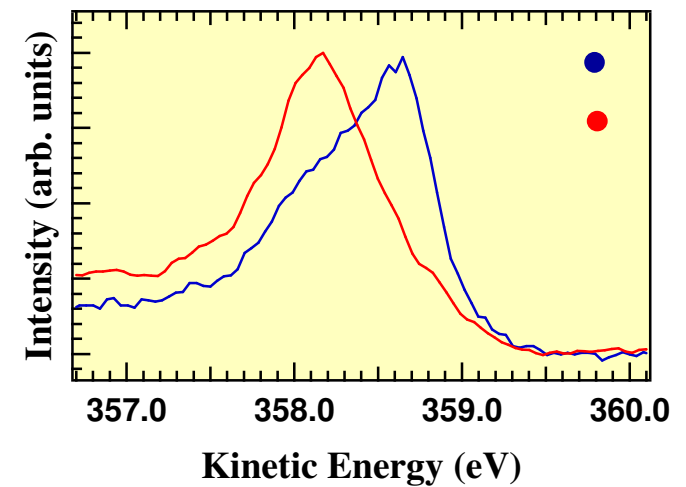
Ru(0001) oxidation
H. Conrad – FHI - Germany

Ru 3d maps

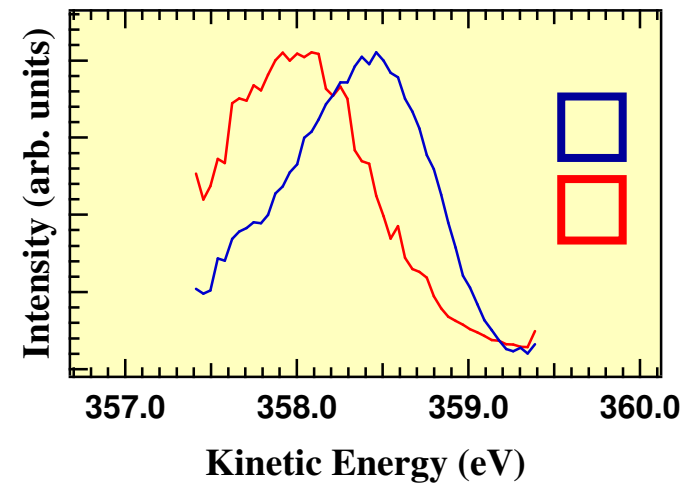


Ru 3d_{5/2} spectra

Conventional Scanning
Spectroscopy (48 points - 70 sec)



Inherent Dispersion Energy
Spectroscopy (48 points - 10 sec)



References

S. Guenther, B. Kaulich, L. Gregoratti, M. Kiskinova, "Photoelectron Microscopy and Applications in Surface and Material Science", PROG SURF SCI, 70-, pp. 187-74 (2002).

A.W. Potts, G.R. Morrison, L. Gregoratti, A. Barinov, B. Kaulich, M. Kiskinova, "The exploitation of multichannel detection in scanning photoemission microscopy", SURF REV LETT, 9-2, pp. 705-8 (2002).

L. Gregoratti, A. Barinov, E. Benfatto, G. Cautero, C. Fava, P. Lacovig, D. Lonza, M. Kiskinova, R. Tommasini, S. Mahl, "48-Channel electron detector for photoemission spectroscopy and microscopy", REV SCI INSTRUM, 75-1, pp. 68-4 (2004).